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# STRUCTURE AND METHOD FOR RESURF DIODES WITH A CURRENT DIVERTER

## TECHNICAL FIELD

This invention generally relates to Smart Power integrated circuits and, more particularly, to means and methods for reducing substrate leakage currents associated with RESURF diodes employed in such integrated circuits.

## BACKGROUND

There are many integrated circuit (IC) applications today in which a diode is formed by using a source region and gate terminal of a metal oxide semiconductor field effect transistor (MOSFET) shorted together forming an anode (or cathode), and what would ordinarily be the drain region of the MOSFET acting as the cathode (or anode) of the diode. Such structures are particularly useful in connection with RESURF devices. "RESURF" is an abbreviation standing for "reduced surface field." RESURF devices and method are described for example, in U.S. Pat. No. 6,882,023 B2 to Khemka et al and U.S. Pat. No. 6,747,332 B2 to de Fresart et al.

A known RESURF diode device is illustrated in FIG. 1, which shows a simplified schematic cross-section through double RESURF MOSFET diode device 20. RESURF MOSFET structures and methods are well known in the art and much used in power ICs. RESURF diode device 20 comprises P substrate 22, N-type buried layer (NBL) 24 overlying substrate 22, P-epi region 26 overlying NBL 24, P-buried region 28 typically implanted within P-epi region 26, N-well region 30 located between P-buried region 28 and surface 35, P-body region 32 extending into P-epi region 26 from surface 35 and laterally separated from N-well region 30 by channel region 27, N+ sinker region 34 extending from surface 35 through P-epi region 26 to NBL 24, N+ contact region 36 at surface 35 in N+ sinker region 34 for making contact to NBL 24 via N+ sinker region 34, P+ (e.g., anode) region 38 in P-body region 32 laterally separated from N+ contact region 36 by oxide (OX) isolation region 40, MOS gate 42 located over surface 35 above portion 33 of P-body region 32 extending laterally from P+ anode region 38 across channel region 27 and portion 31 of N-well region 30 and separated therefrom by thin gate oxide 43 on surface 35. Isolation oxide (OX) region 44 is provided vertically extending from surface 35 into N-well region 30 and laterally extending approximately from edge 42-1 of gate 42 to N+ cathode region 46 in N-well region 30 at surface 35. Connection 39 with lead 29 coupling P+ anode region 38 and gate 42 forms the anode contact of RESURF diode device 20 and connection 47 to N+ region 46 forms the cathode contact of RESURF diode device 20. Connection 41 is typically provided tying BL contact 37 to cathode connection 47.

FIG. 2 is simplified electrical equivalent circuit 50 of diode 20 of FIG. 1. Equivalent circuit 50 comprises PN diode 52 and PNP parasitic transistor 54 inherently present in RESURF diode device 20 of FIG. 1. PN diode 52 is provided by anode region 38 with contact 39 in P-body 32 and cathode region 46 with contact 47 in N-well 30. Parasitic PNP transistor 54 is provided by P-epi region 26, P-body 32 and contact region 38 that act as emitter 55; NBL 24 that acts as base 56; and P substrate 22 that acts as collector 57. Base 56 is coupled to cathode contact 47 via N+ sinker region 34, N+ contact region 36 and connection 41. While the arrangement of FIGS. 1-2 provides a convenient diode that is easily manufactured in connection with RESURF integrated circuits, it suffers from a number of well-known disadvantages. For example and not

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intended to be limiting, parasitic transistor 54 provides a leakage current path to substrate 22 as the forward bias across diode 52 is increased. This is undesirable and can degrade overall performance of the integrated circuit within which the diode of FIGS. 1-2 is incorporated. Thus, there continues to be a need for improved diodes that are process compatible with RESURF and other types of integrated circuits.

Accordingly, it is desirable to provide an improved integrated circuit diode structure and method that is compatible with integrated circuit technology, especially MOSFET integrated circuit technology and most particularly RESURF type MOSFETs. In addition, it is desirable that the improved diode structure and method be achievable with little or no change in established manufacturing processes, preferably, accomplished merely by modification of the masking layer(s) used for fabrication of the integrated circuits without having to add additional process steps. Furthermore, other desirable features and characteristics of the invention will become apparent from the subsequent detailed description and the appended claims, taken in conjunction with the accompanying drawings and the foregoing technical field and background.

## BRIEF DESCRIPTION OF THE DRAWINGS

The invention will hereinafter be described in conjunction with the following drawing figures, wherein like numerals denote like elements, and

FIG. 1 is a simplified schematic cross-section through a known double RESURF diode device;

FIG. 2 is a simplified electrical equivalent circuit of the diode device of FIG. 1;

FIG. 3 is a simplified schematic cross-section through a RESURF diode device according to a first exemplary embodiment of the invention;

FIG. 4 is a simplified electrical equivalent circuit of the diode device of FIG. 3;

FIG. 5 is a simplified schematic cross-section through a RESURF diode device according to a further exemplary embodiment of the invention;

FIG. 6 is a simplified electrical equivalent circuit of the diode device of FIG. 5;

FIG. 7 is a simplified schematic cross-section through a further known RESURF diode device;

FIG. 8 is a simplified electrical equivalent circuit of the diode device of FIG. 7;

FIG. 9 is a simplified schematic cross-section through a RESURF diode device according to a still further exemplary embodiment of the invention;

FIG. 10 is a simplified electrical equivalent circuit of the diode device of FIG. 9;

FIG. 11 shows plots as a function of forward current of the ratio of substrate current ( $I_{sub}$ ) to diode current ( $I_c$ ) for diode devices of the prior art and the invention of the type illustrated in FIGS. 1 and 3; and

FIG. 12 shows plots as a function of forward current of the ratio of diode current ( $I_c$ ) to substrate current ( $I_{sub}$ ) for diode devices of the prior art and the invention of the type illustrated in FIGS. 7 and 9.

## DETAILED DESCRIPTION

The following detailed description is merely exemplary in nature and is not intended to limit the invention or the application and uses of the invention. Furthermore, there is no intention to be bound by any expressed or implied theory